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New insights into SEE ground
testing on power Mosfets.

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Content

- 1 Aim of the study
- 2 Test definitions & procedure according to MIL STD-750
- 3 Status
- 4 Experimental results analysis
- 5 Conclusion

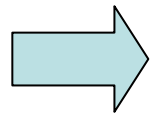
1. Aim of the study

Raise potential issues related to space conditions representativity of SEE power MOSFETs ground-level testing, according to MIL STD-750 spec, or other related (ESA SCC25100, ASTM F-1192..).

2. Test definitions & procedure (MILSTD-750) (1)

SEGR definition

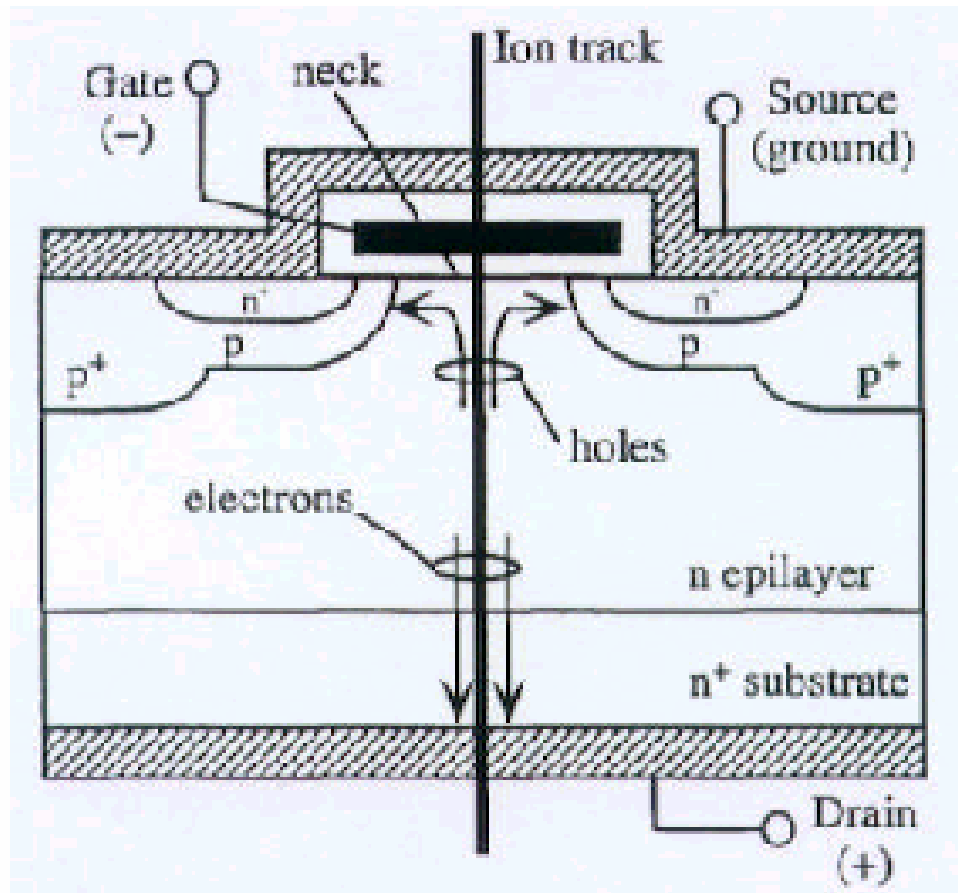
§1.1.i Single-event gate rupture (SEGR): A single-ion-induced condition that causes a localized defect in the gate dielectric resulting in a catastrophic device failure, characterized by an increase in gate current that exceeds the manufacturer's rated leakage current at the gate electrode.



*Comment: typically, I_{gss} max rated = 100 nA.
Designs withstand such “degradation”.*

2. Test definitions & procedure (MILSTD-750) (2)

- Reminder: SEGR (Single Event Gate Rupture : N & P channels)

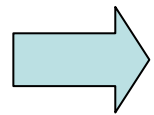


- SEGR is caused by an ion strike in the neck region of the power MOSFET.
- The most complete study so far has shown that SEGR should not become a significant concern if the gate oxide electric field is limited below 5 MV/cm.
- Today, this phenomena is assumed as being probabilistic.

2. Test definitions & procedure (MILSTD-750) (3)

SEGR post gate stress test definition

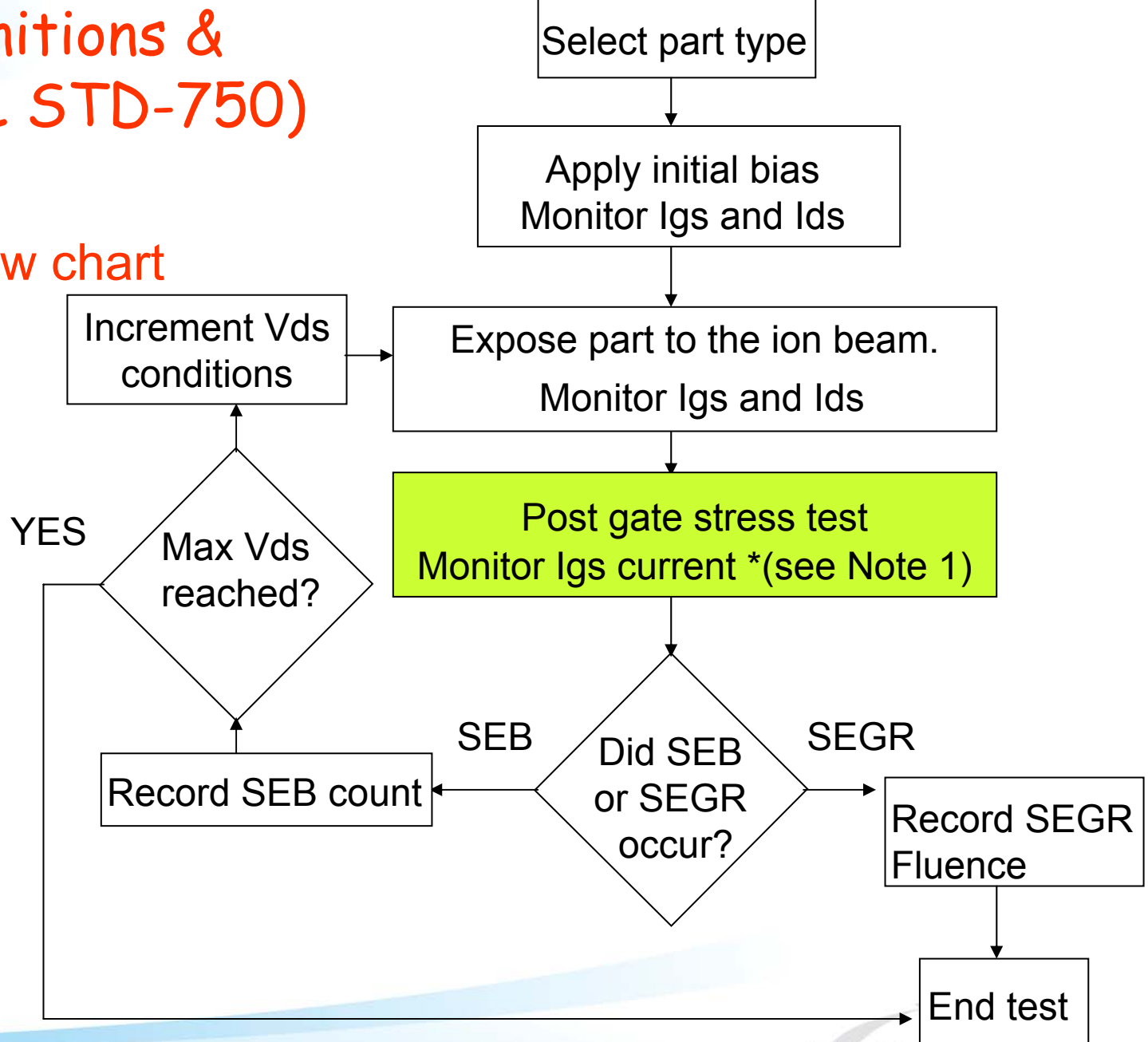
1.1.m. SEGR post gate-stress test: After the heavy ion irradiation, a test is conducted to verify the gate integrity by applying the maximum specified VGS.



Comment: absolute max rating on V_{gsoff} is mostly +/- 20V, with almost no margin.

2. Test definitions & procedure (MIL STD-750) (4)

Characterisation Flow chart



***Note:**
Measurement conditions
I_{gss} : V_{gs}=20V
V_{ds}=0V

3. Status

Most of the designs use MOSFETs with $|V_{gsoff}| \sim 0 \text{ V}$, in compliance with RHA golden rules.

Wealth SEE data on power MOSFETs exist in the literature, websites,....:

- NSREC 1998 Data Workshop, ...
- Manufacturer data...
- ...

These data are obtained according to MIL-STD-750 from experiments performed in static mode.

At $V_{gs}=0\text{V}$ (No over-blocking conditions), the conclusion is SEGR occurrence:

Fluence $\sim > 10^5 \text{ p/cm}^2$

Flux $\sim > 3 \cdot 10^4 \text{ p/cm}^2/\text{s}$

4. Experimental results analysis (1)

Experiments are performed on N & P channels with varying parameters :

- V_{gs} (static or switched)
- Flux

Recorded parameter : I_{gs} , V_{ds} (burnout checked).

4 Experimental procedure (2)

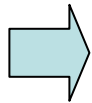
- **PROBLEM ? Continuous drift ? Or ?sharp increase?** of gate current



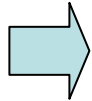
- To be able to measure continuously the Gate leakage current while the Ion beam is focused on the component die.



- Characterize the current drift versus the ion fluence



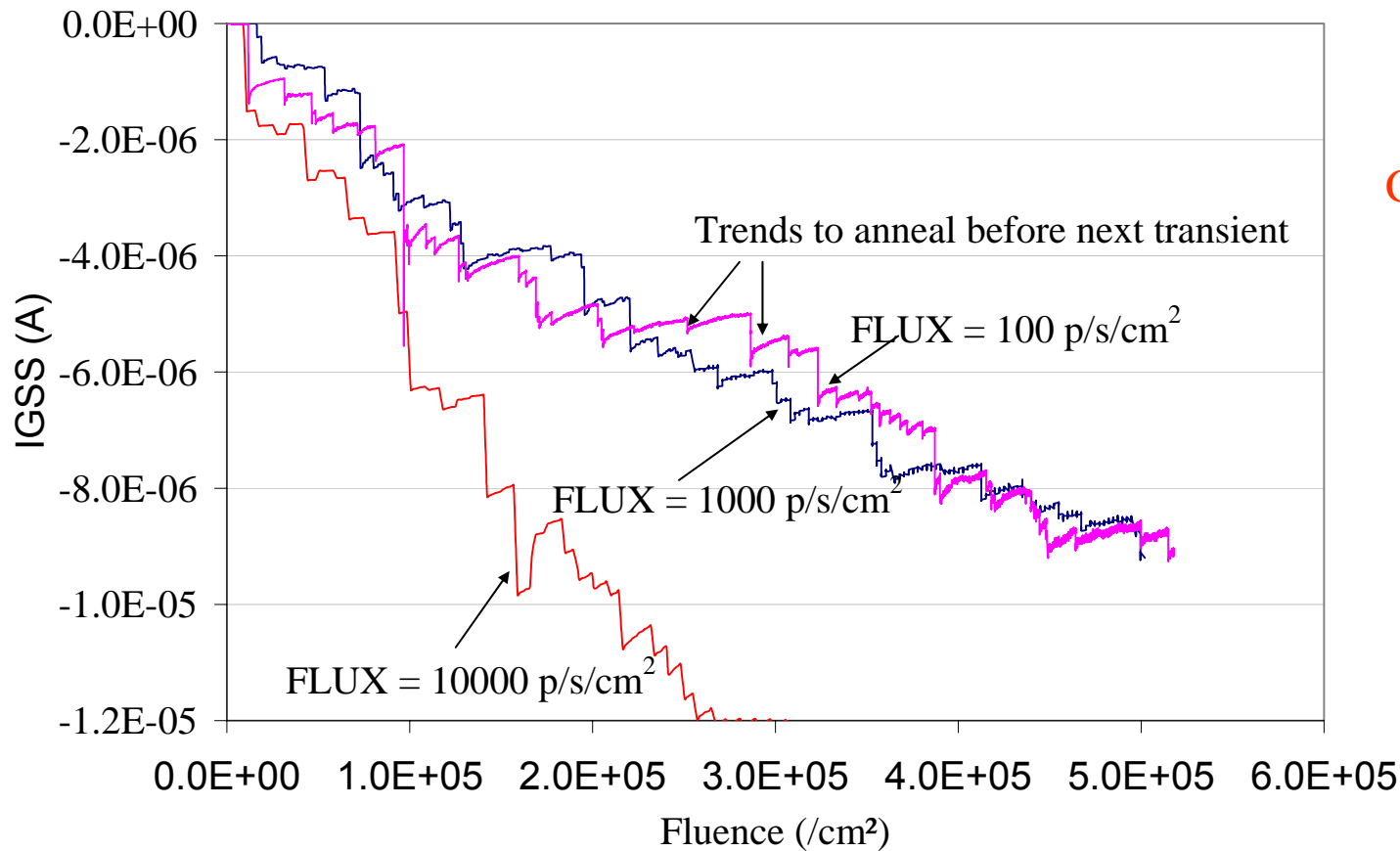
- Measurement has to be done in static and switching modes (DC-DC applications)



- The fluence shall be available at monitoring system level

4. Experimental results : Flux effect in switched mode (N channel) (3)

IRFF110 (N channel) LET = 55.9 MeV.cm²/mg (Xe), Range = 43 μm,
Vds = 80 V, Vgs switched= [-5 V; 10V] , Igss current measured with Vgs = -5 V..

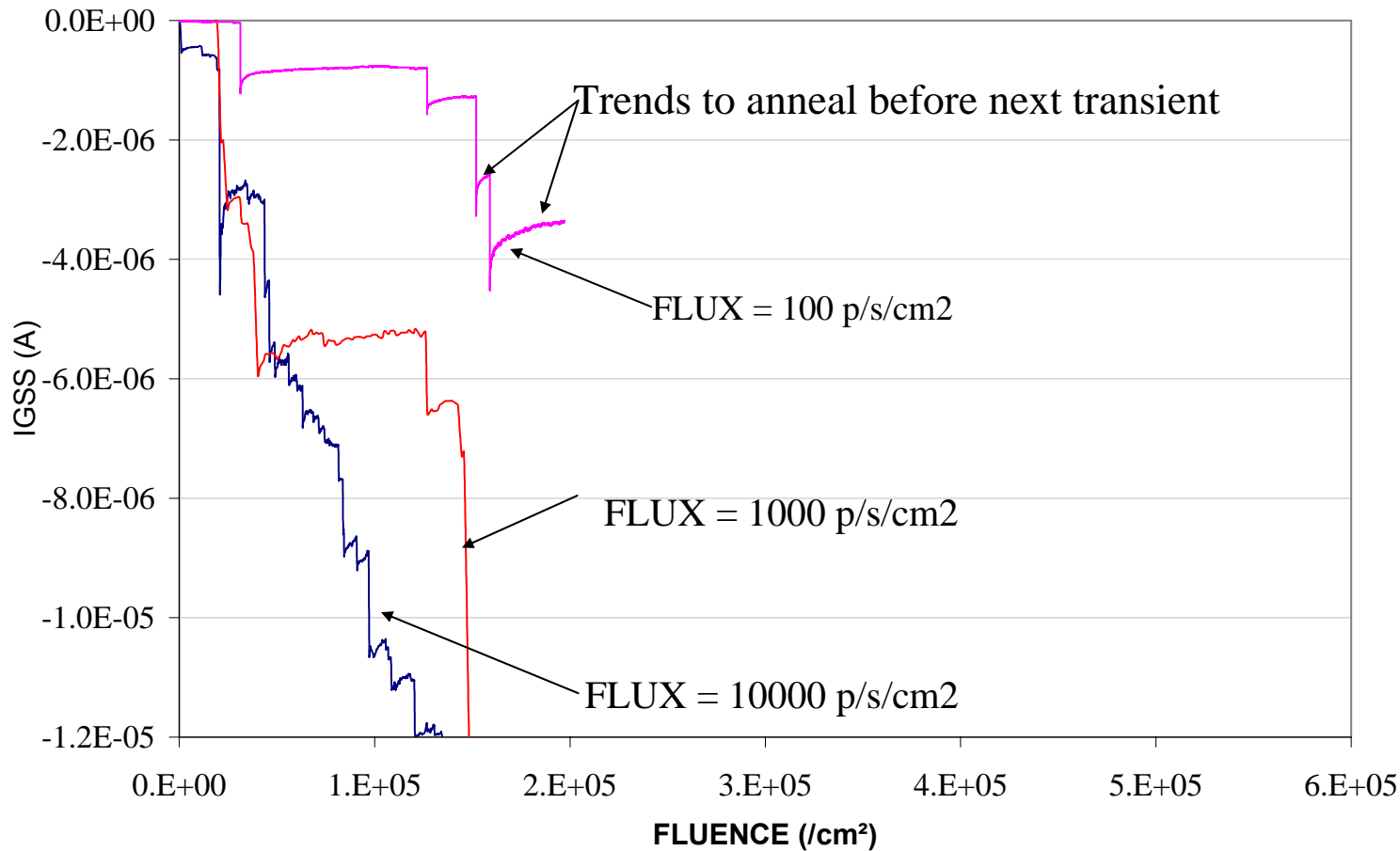


Competition between anneal and flux ?

The highest the flux, the highest degradation rate.

4. Experimental results : Flux effect in static mode (N channel) (4)

IRFF110 (N channel) LET = 55.9 MeV.cm²/mg (Xe), Range = 43 μm, V_{ds} = 80 V, V_{gs} = -5 V, I_{gss} current measured with V_{gs} = -5 V.



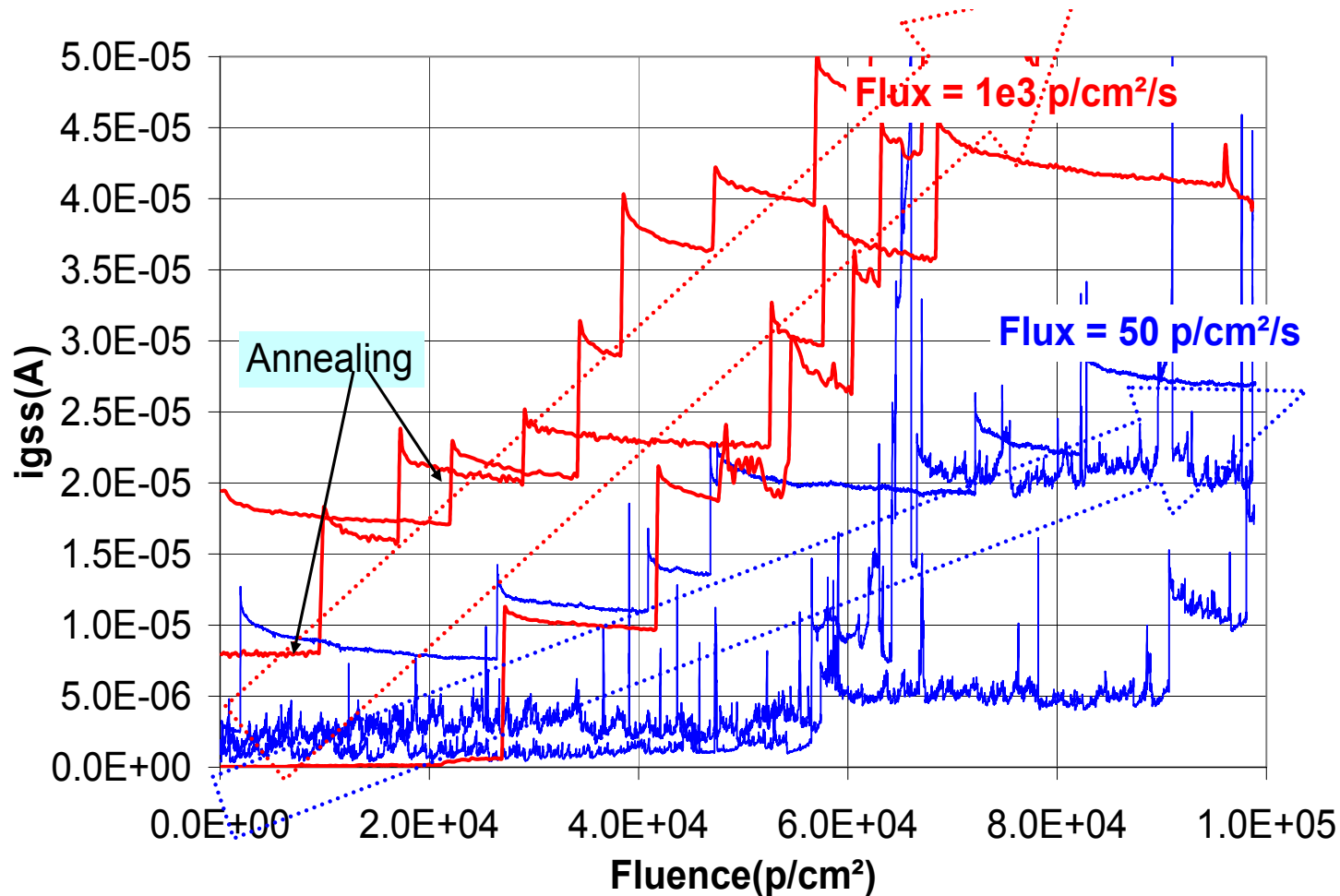
Competition between anneal and flux?

The highest the flux, the highest degradation rate.

4. Experimental results : Flux effect (P channel) (5)

IRFF9120 P channel gate degradations.

LET = 34 MeV.cm²/mg (Kr), Range = 43 μm, V_{ds} = 100 V, V_{gs} = 15 V

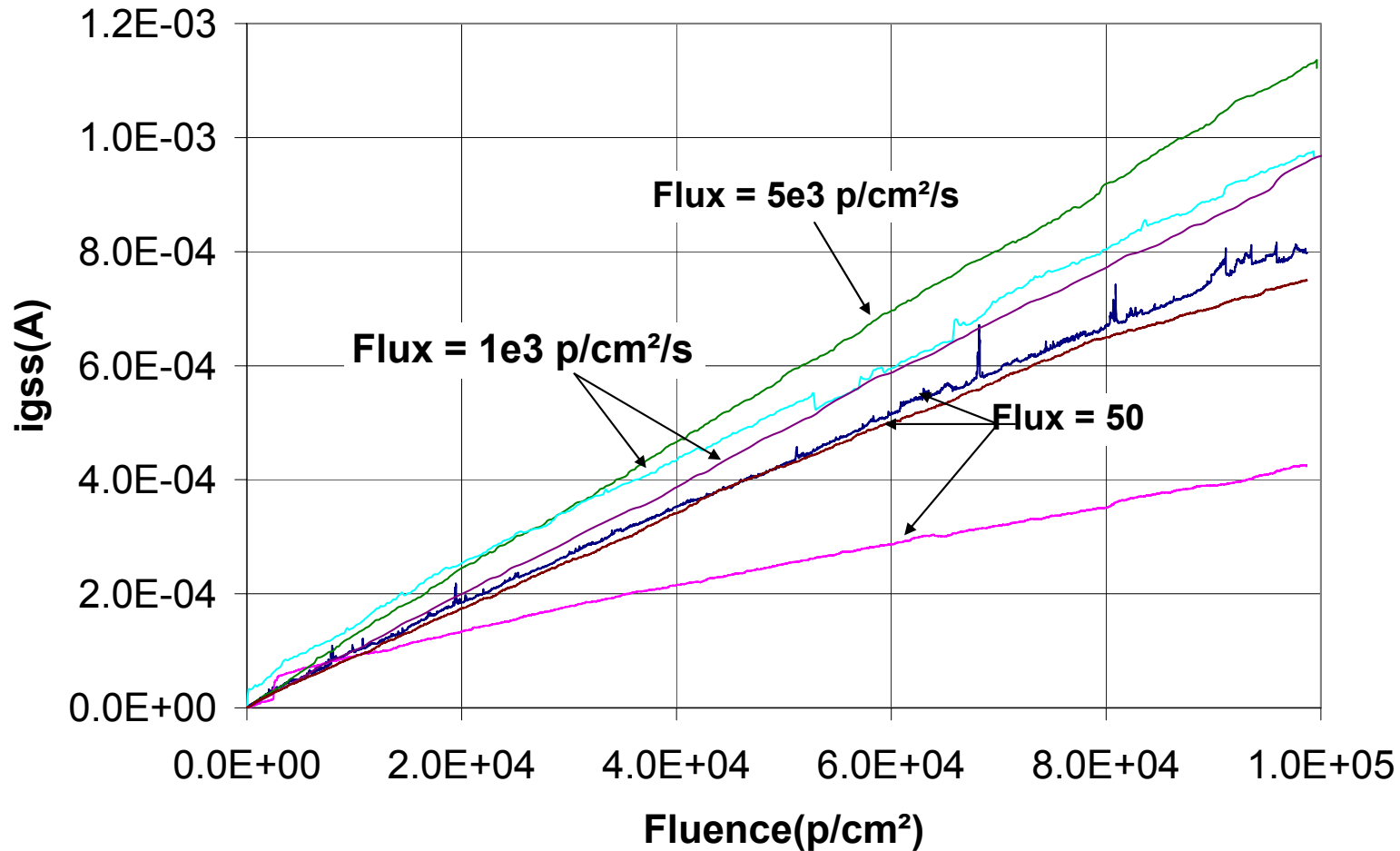


Competition between anneal and flux?

The highest the flux, the highest degradation rate.

4. Experimental results : Flux effect (P channel) (6)

STB80PF55 gate degradation for several fluxes. $V_{ds}=-55V$,
 $V_{gsoff}=15V$. K_r (LET =34, Range = 43 μ)



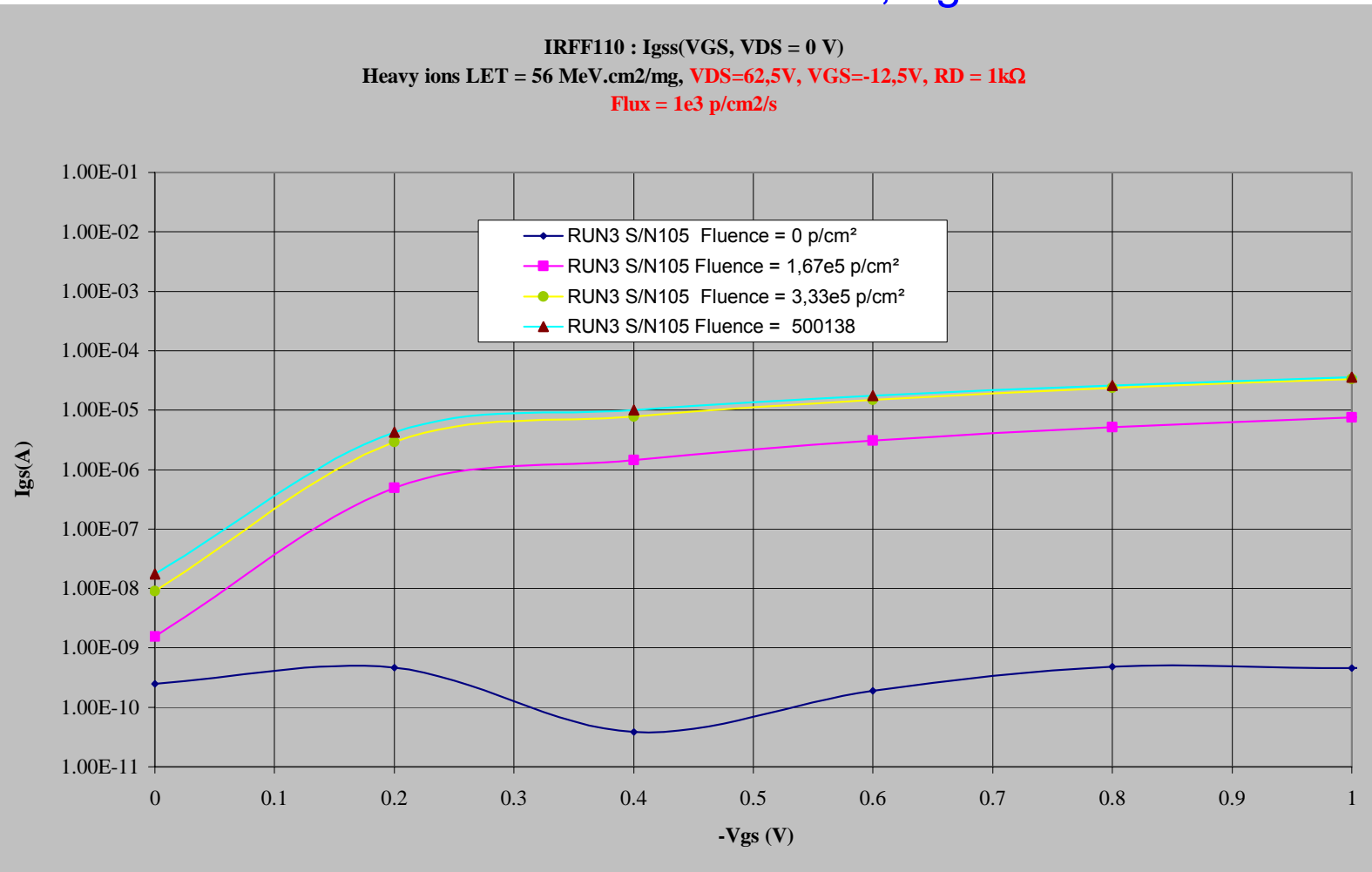
4. Experimental results : Post gate stress test (IRFF110, 100V N channel) (7)

$I_{gs}(V_{gs}, V_{ds}=0V)$ post-irradiation measurement.
Irradiation conditions: $V_{ds}=62V, V_{gs}=-12V$

« SEGR » status is dependent on the V_{gs}

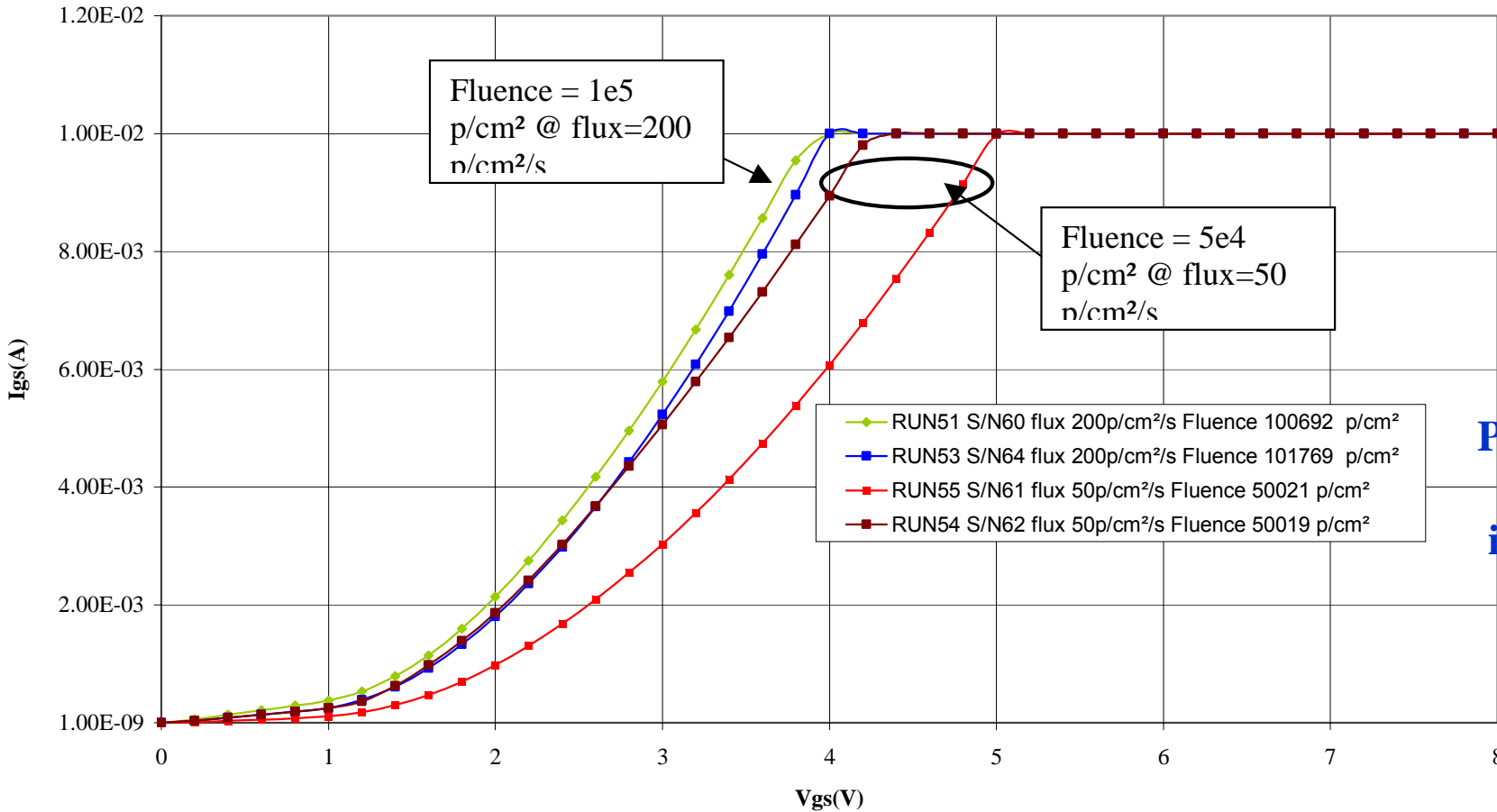
At $V_{gs} = 0V$,
Negligible leakage.

Perfectly working
transistor
in switched mode
($V_{gsoff}=0$)



4. Experimental results : "Post gate stress test" (STP80 NF10, 100V N channel) but with $V_{ds} \neq 0$ (8)

STP80NF10 : $I_{gss}(V_{GS}, V_{DS} = 50 \text{ V})$
Heavy ions LET = 56 MeV.cm²/mg, $V_{DS}=50\text{V}$, $V_{GS} = 0$ Static, $R_D=1000 \ \Omega$

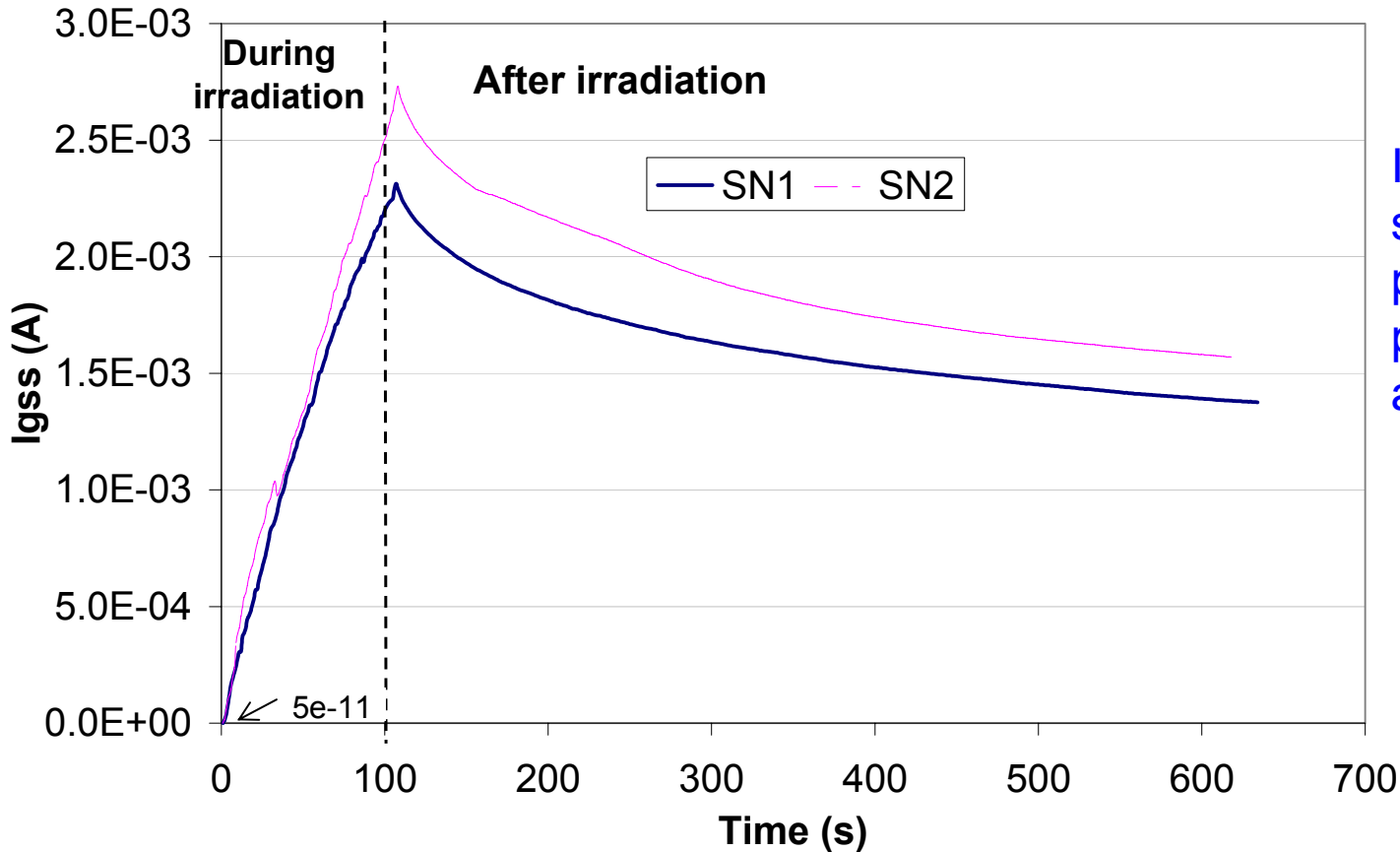


I_{gs} ($V_{gs}=0$) negligible

Perfectly working transistor in switched mode ($V_{gsoff}=0V$)

4. Experimental results : ΔI_{gss} Annealing (P channel) (9)

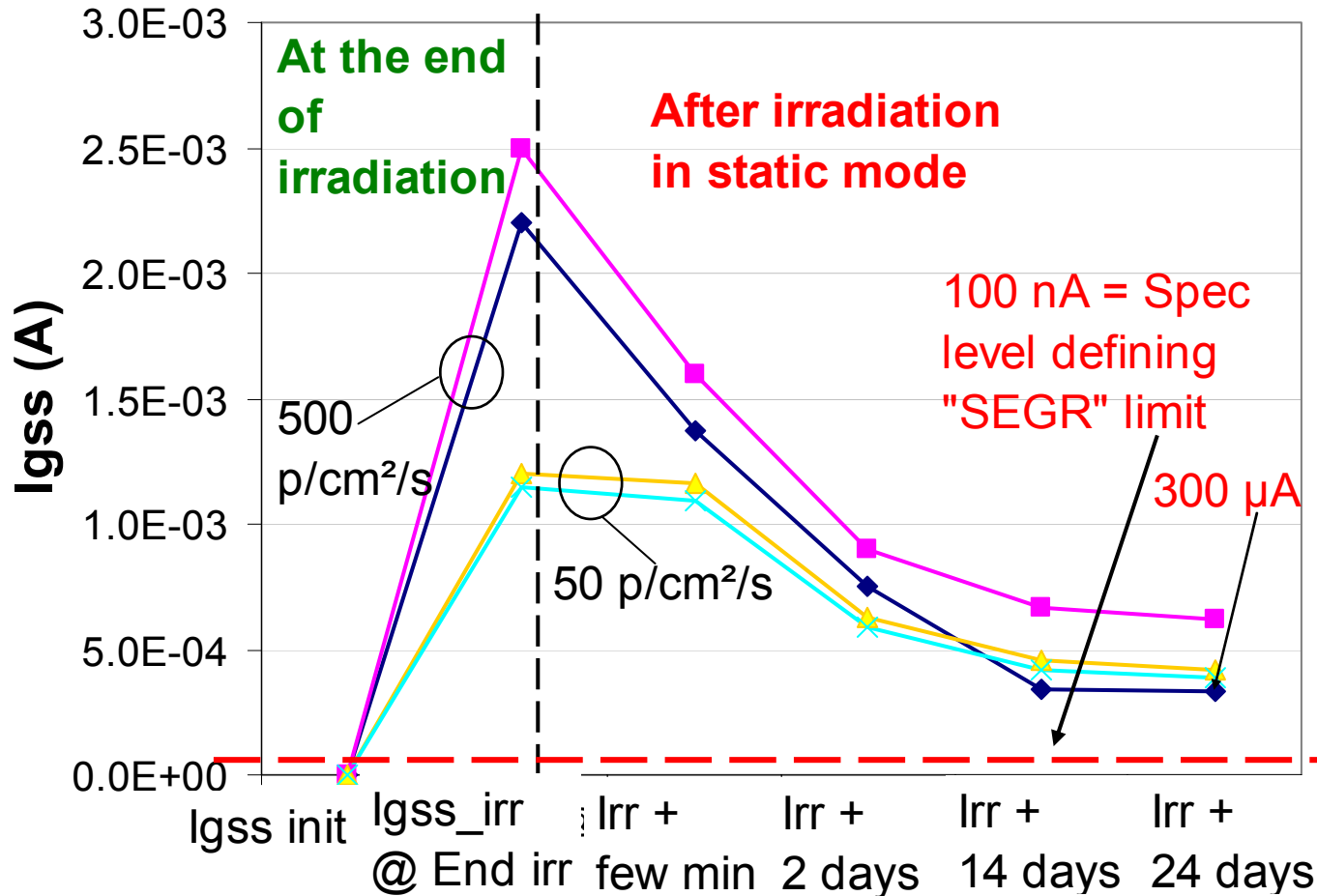
I_{gss} evolution during and after irradiation STB80PF55,
(P channel, $V_{ds} = 80\%$, $V_{gs} = +5\text{ V}$), Kr (LET =34, Range =92 μ),
flux = 500 p/cm²/s, Fluence $\sim 5e4$ p/cm²



$I_{gs}(V_{gs})$ would lead to same type of curve as previously (STP80NF10) if performed immediately after irradiation.

4. Experimental results : ΔI_{gss} Annealing (P channel) (10)

STP80PF55 I_{gss} anneal



Competition between anneal and flux

$I_{gs}(V_{gs})$ would lead to same type of curve as previously (STP80NF10) if performed immediately after irradiation.

This curve would be different after anneal

Flux effect on P channel STB80PF55 gate degradation annealing, after $5e4$ p/cm², LET=34, Range=92 μ .



4. Experimental results : preliminary conclusion on gate degradation (11)

ΔI_{gss} negligible at $V_{gs}=0V$

Switched mode exhibits lower degradation rate

Every parts could perfectly switch [$V_{gsoff}=0$, V_{gson}]

Anneal at ambient T° showed an I_{gss} recovery of $>\sim 2$ mA :

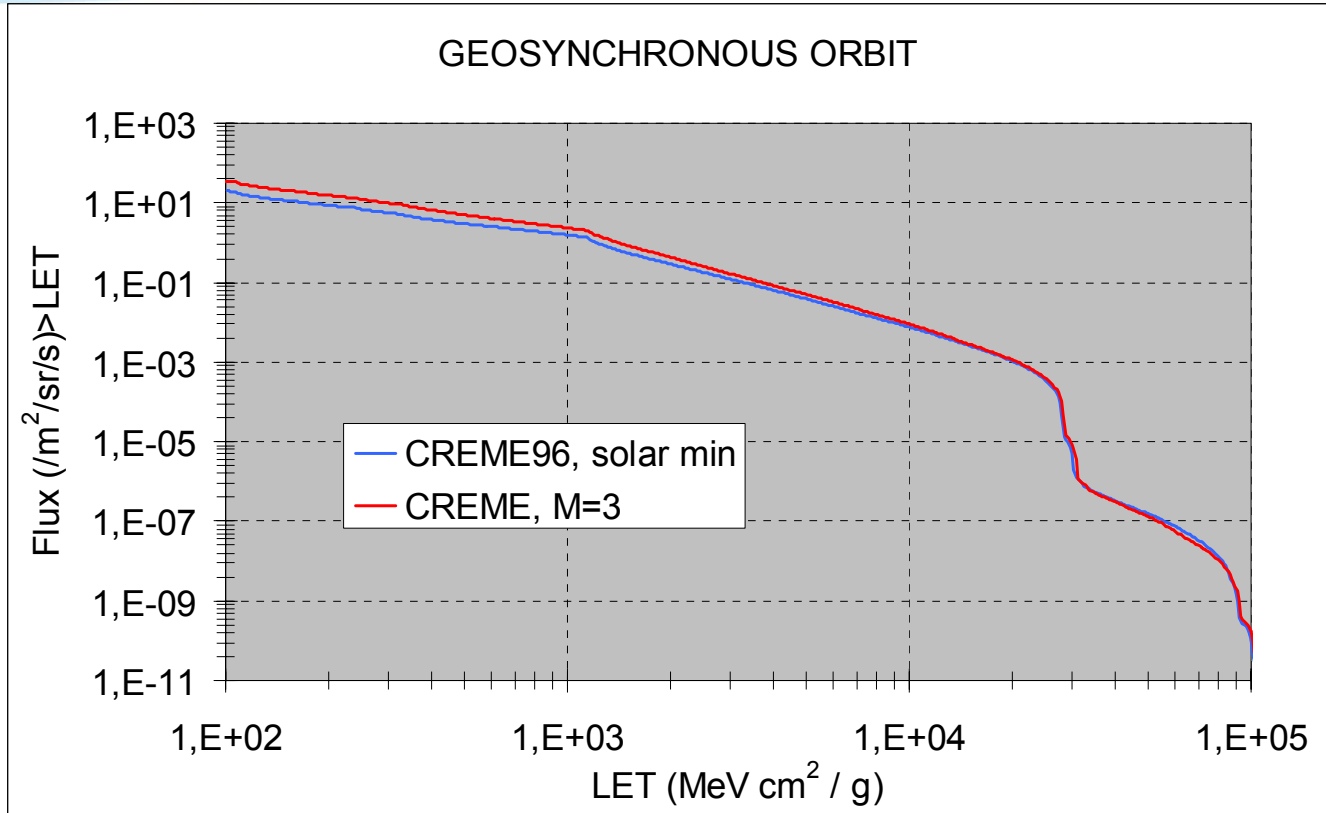
 a $\Delta I_{gss} \geq \sim 100$ nA (spec. definition of “SEGR”) is expected to recover.

According to MIL STD-750 spec, parts would be rejected since $\Delta I_{gss} > 100$ nA after several 10^5 p/cm² !

No proof that gate degradation measured at V_{gsoff} max-rated (post gate stress test, i.e. almost dielectric avalanche conditions) is related to a “single ion”.

The lower the flux, the lower the gate degradation rate: a cumulative phenomena is highlighted, especially far from avalanche conditions.

5. CONSEQUENCES (1)

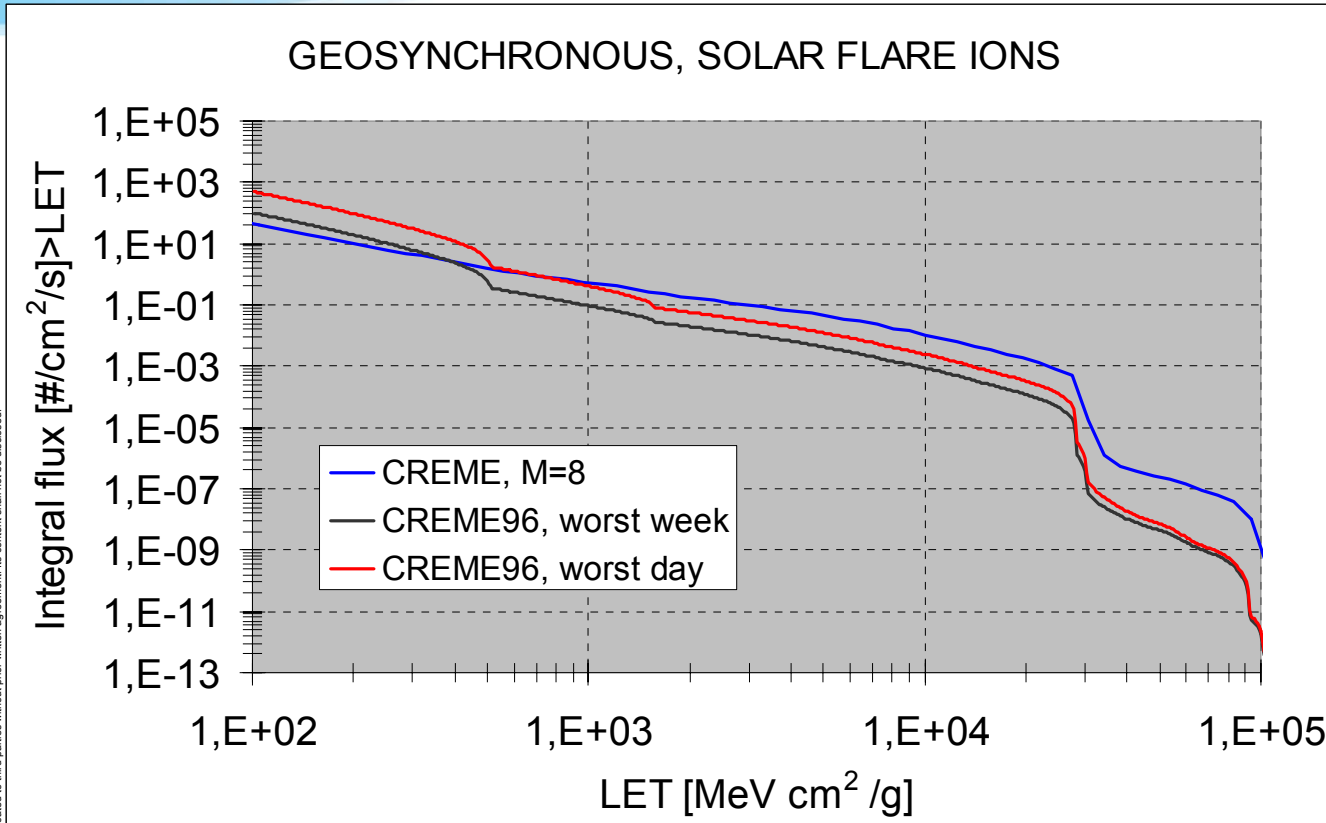


➤ Mission duration : 15 years

Total fluence @ LET ~ $5,6e4 \text{ MeV/cm}^2/\text{g}$, after 15 years @ M=3:

**Space fluence : $\Phi = 5e-2 \text{ p/cm}^2$, at space flux ~ $1e-10 \text{ p/cm}^2/\text{s}$ to be compared
to test fluence : $\Phi = 1e5 \text{ p/cm}^2$ at test flux [$1e3 ; >1e4$] $\text{p/cm}^2/\text{s}$**

5. CONSEQUENCES (2)



➤ Flare duration
= 4*4days in 15
years

➤ Total fluence @ LET ~ 5,6e4 MeV/cm²/g after 16 solar flare days :

Space fluence : $\Phi = 0.20$ p/cm², at space flux ~ 1e-7 p/cm²/s to be compared to
test fluence : $\Phi = 1e5$ p/cm² at test flux ~ [1e3 ; >1e4] p/cm²/s

6. CONCLUSION

Based from these experimental results, one can conclude the following:

- Gate degradation appears to be a **cumulative** effect mainly driven by the **high flux** used for ground testing.
- Gate degradation as being defined by specification as single ion related appears to be questionable (Post-gate stress test).
- “SEGR” defined as a pure probabilistic phenomenon is questionable.
- « SEGR » phenomena is expected as **improbable** in SPACE conditions, especially within no over-blocking conditions (far from dielectric avalanche conditions).
- Non RH Channel P Mosfet could be used for space applications (GEO and LEO) especially if used far from dielectric avalanche conditions
- Further investigations are necessary that will most probably lead to an upgrade of the testing standards.